

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of :
Oka et al. :
Application S/N: New Application : Group Art Unit: Unassigned
Filed: Concurrently herewith : Examiner: Unassigned
For: CRYSTALLINE SILICON THIN FILM SEMICONDUCTOR DEVICE,
CRYSTALLINE SILICON THIN FILM PHOTOVOLTAIC DEVICE, AND PROCESS
FOR PRODUCING CRYSTALLINE SILICON THIN FILM SEMICONDUCTOR DEVICE

PRELIMINARY AMENDMENT

Honorable Assistant
Commissioner
for Patents
Washington, DC 20231

Sir:

This preliminary amendment is directed to the above-referenced application. Prior to examination, please amend the application as follows:

IN THE CLAIMS

Please amend claims 9-10 and 16 as follows:

Subc 7 9. The crystalline silicon thin film semiconductor device according to claim 6, wherein the fourth polycrystalline silicon layer has the same crystallographic orientation as the third polycrystalline silicon layer.

*Oka
Cure*